

# United States Patent [19]

Flamm et al.

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# [54] PROCESS OPTIMIZATION IN GAS PHASE DRY ETCHING

[75] Inventors: Daniel L. Flamm, 476 Green View Dr., Walnut Creek, Calif. 94596; John P.

Verboncoeur, Hayward, Calif.

[73] Assignee: Daniel L. Flamm, Walnut Creek, Calif.

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156/346 P; 156/626.1; 156/659.11; 156/646.1; 204/298.31; 204/298.32; 216/58; 216/59

626.1, 646.1, 659.1, 662.1, 659.11

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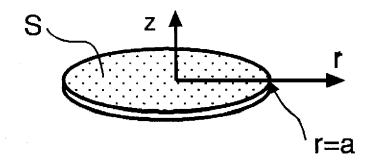
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Primary Examiner—Martin Angebranndt
Attorney, Agent, or Firm—Townsend and Townsend and
Crew LLP

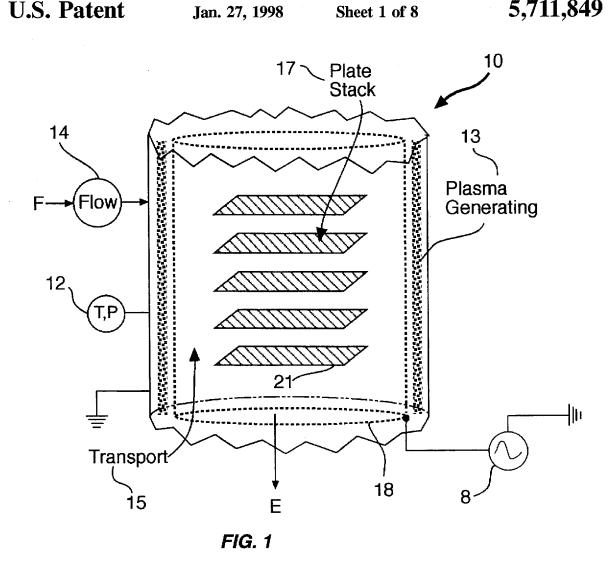
### [57] ABSTRACT

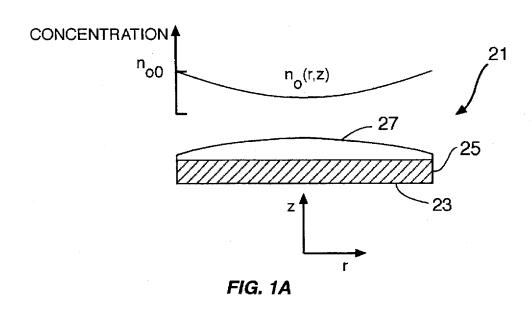
A method of designing a reactor 10. The present reactor design method includes steps of providing a first plasma etching apparatus 10 having a substrate 21 therein. The substrate includes a top surface and a film overlying the top surface, and the film having a top film surface. The present reactor design method also includes chemical etching the top film surface to define a profile 27 on the film, and defining etch rate data from the profile region. A step of extracting a reaction rate constant from the etch rate data, and a step of using the reaction rate constant in designing a second plasma etching apparatus is also included.

## 29 Claims, 8 Drawing Sheets



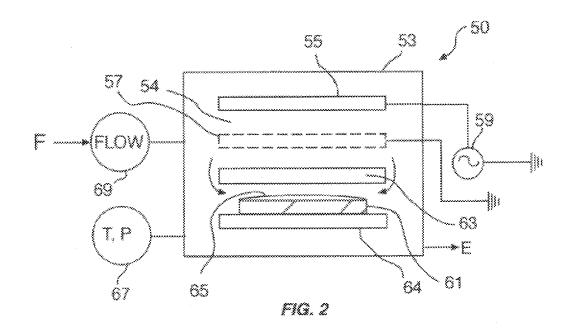


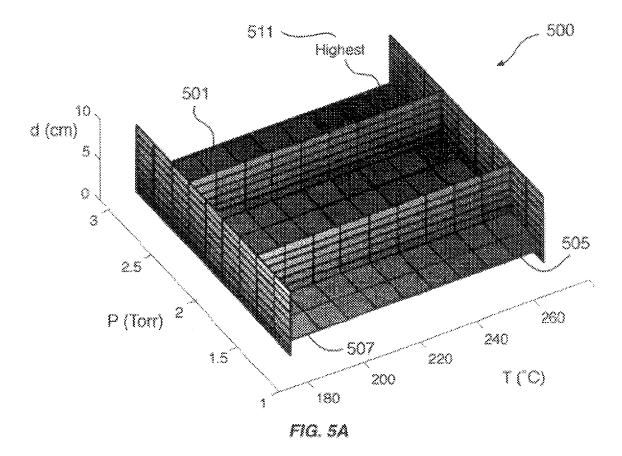






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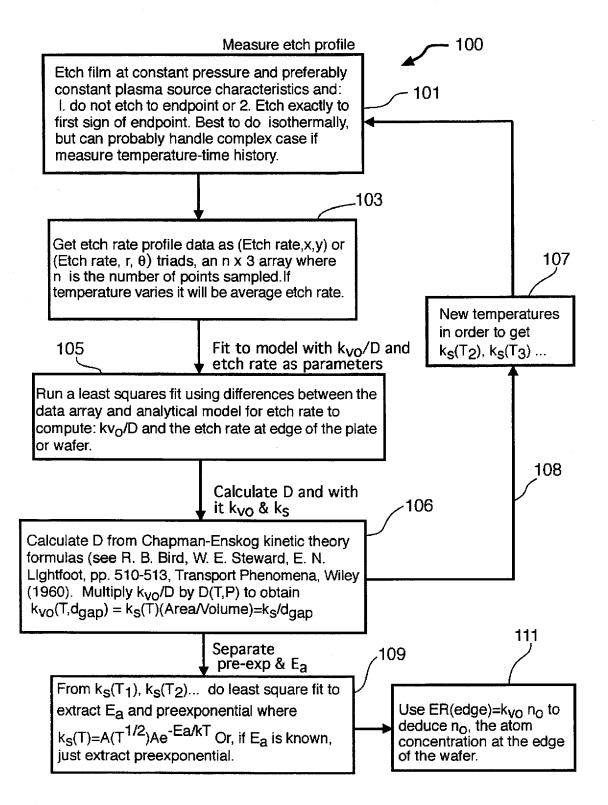


FIG. 3

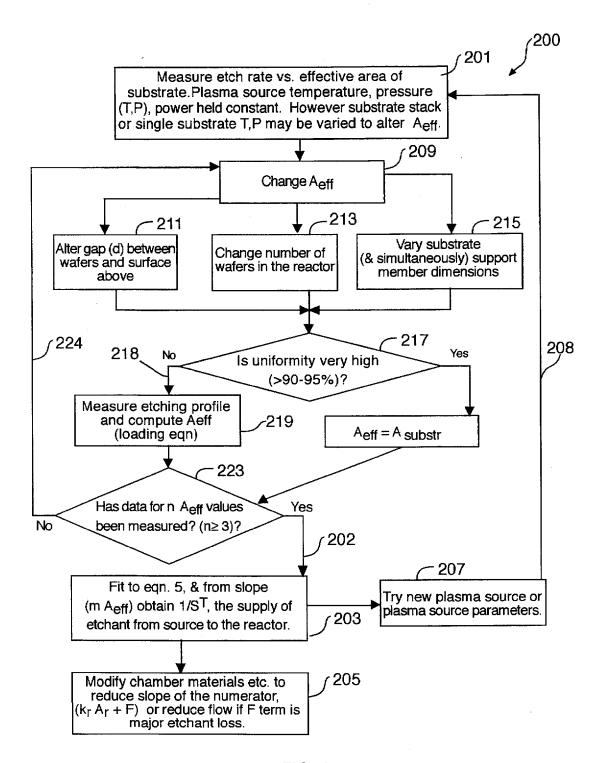


FIG. 4



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